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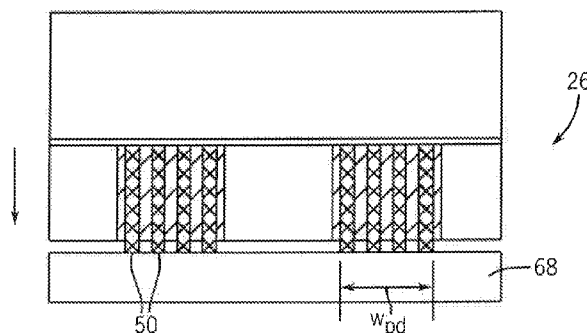
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FIG. 17



(57) Abstract: Methods for fabricating stamps and systems for patterning a substrate, and devices resulting from those methods are provided.

